Parameter	**GeminiSEM 300 with a 3View2XP**
Resolution	0.8 nm at 15kV; 1.4 nm at 1kV
Accelerating Voltage	<1kV - 5kV
Probe Current	3pA - 20 nA
Charge Neuralization	5 - 40 Pa is typical at 2kV
Cut Speed	Recommended speed: 0.5 - 1 mm/s
Cut Thickness	25 - 50 nm to analyze cell structure
Pixel Dwell Time	1 -20 μs
Image Scanning	Single pass or multiple frames
Imaging modes	Single frame per cut; Multiple fields of view and magnifications per cut; stage montage for large fields of view

Table 1: Table of technical specifications for a Zeiss Gemini300 SEM with a 3View2XP.